



General introduction to three-dimensional cryo-microscopy

Winter School on Structural Cell Biology

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Introduction

Three-dimensional cryo-microscopy

A concept that encompasses leading methods in **electron microscopy** for **three-dimensional structure** determination of biological samples, from macromolecules to cells, **in close to native conditions** (vitrified samples).

Cryo-EM: The challenges

 Samples that have to be studied in their hydrated state to ensure structural preservation

VITRIFICATION

converts liquid water into amorphous ice

- SAMPLE PREPARATION • Suitable sample thickness to obtain molecular resolution
- Low-contrast due to weakly scattering building blocks

Advance Micromachining **ADVANCE 3D CORRELATION**

POOR IMAGING CONDITIONS **OPTIMIZE INSTRUMENTATION** E.G. DETECTORS & PHASE **PLATES**

Sensitivity to ionizing radiation -

LOW DOSE METHODS **ADVANCE AUTOMATION**



TEM HISTORY: An Anecdote...

"You know," Szilard told Gabor over a café table in 1927, now that it is possible to make electron lenses, "why do you not make a microscope with electrons?" At smaller and smaller wavelengths, you would achieve much more detailed resolution than is possible with microscopes using light. Gabor and Szilard pondered his idea for a few minutes, then agreed it would serve no useful purpose. After all, you could not put living matter into the kind of vacuum tube needed to control electron beams. Besides, they concluded, so much power would be focused in the electron beam that it would incinerate any sample.

But as Gabor later realized, with that idle suggestion Szilard had grasped the possibility of an electron microscope at least a year before anyone else. And of the incinerated sample, Gabor later wrote, "Who would have dared to believe that the cinder would preserve not only the structure of microscopic bodies but even the shapes of organic molecules?" Gabor would be remembered years later as the inventor of holography, for which he received the 1971 Nobel Prize in physics.¹⁵

William Lanouette. Genius in the Shadows, A Biography of Leo Szilard, the Man Behind the Bomb



WHY?: Microscopy with electrons

At smaller and smaller electron wavelengths, one can achieve much more detailed resolution than with light.

The wavelength of an electron is given by the de Broglie equation:

$$\lambda_{electrons} = \frac{h}{mv} \approx \frac{h}{\sqrt{2m_0 E(1 + \frac{E}{2m_0 c^2})}}$$

| energy E [keV] | wavelength λ [Å] | velocity v [km/sec] |
|----------------|--------------------------|---------------------|
| 20 | 0.086 | 76000 |
| 40 | 0.06 | 107000 |
| 60 | 0.059 | 131000 |
| 80 | 0.042 | 152000 |
| 100 | 0.037 | 170000 |
| 300 | 0.019 | 233000 |
| 1000 | 0.009 | 282000 |

 \rightarrow Transmission electron microscopes can resolve details down to 1 Å!



Some highlights in TEM history



1931 Technical University, Berlin

| 1897 | J.J. Thomson | Discovered the electron (as a 'corpuscle') | |
|------|--|--|--|
| 1924 | Louis de Broglie | Predicted the wavelength for the electron $\lambda = h/mv$ | |
| 1926 | H. Busch | Magnetic and electric fields act as lenses for electrons | |
| 1927 | G.P. Thomson/ C.J. Davisson and L.H. Germer | Observed the wave properties by electron diffraction | |
| 1931 | M. Knoll & E. Ruska | Built the 1 st electron microscope (EM) | |
| 1936 | Metropolitan Vickers | Manufactured the 1 st industrial EM (EM1) | |
| 1938 | B. von Borries & E. Ruska | Produced the 1 st practical EM (Siemens) – 10 nm resolution | |
| 1939 | Siemens&Halske | Started their commercial EM production | |
| 1962 | R. Castaign & L. Henry | Built the 1 st energy filter | |
| 1982 | P.T.E Roberts et al. | Used the 1 st CCD's for EM | |
| 1986 | E. Ruska/ G. Binning and H. Rohrer | Received the Nobel Prize for TEM and STM | |

E. Ruska und M. Knoll: Die magnetische Sammelspule für schnelle Elektronenstrahlen. Z. techn. Physik. Band 12, 1931, 389–400 und 448

M. Knoll und E. Ruska: Das Elektronenmikroskop. Z. Physik 78, 1932, 318-339.



Electron Microscope - basics



Lučić et al. JCB (2014)



The Gun: Types of Emitters





THE LENSES: Electron Optics



Electrons are manipulated using electromagnetic lenses.

The electron beam coming from the gun is focused and shaped with the help of condenser lenses and apertures. The objective lens and the projection system are used to obtain and magnify a diffraction pattern or the real image.



Optical Aberrations



 $r_{sph} = C_s \beta^3$





Objective Lens



Phase contrast can be described by the Phase Contrast Transfer Function, which highly depends on the instrument and the imaging conditions





Electron-sample interactions





Inelastic Scattering

- The amount of inelastic scattering increases with specimen thickness.
- Inelastic Mean Free Path (MFP), which is a dimension that indicates the path-length inside the specimen wherein all electrons (statistically speaking) will have undergone one inelastic scattering event.



• Typical mean free paths are of the order of : 050-100 nm for 120kV 100-200 nm for 200kV 150-300 nm for 300kV.



Inelastic Scattering...& magnetic prism!





'Zero-loss' filtering





Methods: Instrumentation



FEI Titan Krios

Transmission Electron Microscope

FEI[™] Titan Krios

Some Properties:

- Electron Gun: FEG operated at 300 KeV
- Automated & robotic sample transfer
- Automated data acquisition/ remote controlled
- Stable goniometer with capabilities for dual-axis tilt tomography



Three Branches of Tridimensional Electron Microscopy



crystallography

Single-particle analysis (SPA)

Cryo-Electron Tomography (CET)







Acquire as many images as possible (>= 100-200)

Over the largest possible angular range (+/- 70°)

At the 'lowest' possible dose (~ 50-100 e⁻/A²)



Radiation damage



Dose = current density per unit area j (A/cm²) multiplied by the exposure time t (s) (C/cm², or e⁻/Å², e⁻ = electrons)



Electron Dose: Signal&Noise



→ vitrified chromatophore vesicles in *Rhodobacter sphaeroides (Falcon I)*



Low Dose Acquisition scheme





Cryo-electron tomography



Single-axis tilt ECT

Single-axis tilt Electron Cryotomography

A tilt series is recorded in a TEM by rotation of the sample holder around one axis, usually ca. 120 degrees.

Aim: 3D reconstruction of the imaged object.



Missing Wedge Problem





Cryo-electron tomography



Dual-axis tilt Electron Cryotomography

Two orthogonal tilt series from the same object are recorded in a TEM.

Aim:

To gain isotropic resolution for higher fidelity of macromolecular complexes recognition.



Missing wedge

Limited tilt range implies an unsampled region (information is missed)



Fourier space

Real space



| Tilt range | Single | Double |
|------------|--------|--------|
| ±70° | 78% | 93% |
| ±60° | 67% | 84% |
| ±45° | 50% | 67% |

(Lucić, V., et al, Annual Review of Biochemistry, 2005)



"Cryo-Electron Microscope" concept

NEW APPROACHES IN CORRELATIVE STUDIES OF BIOLOGICAL ULTRASTRUCTURE BY HIGH-RESOLUTION ELECTRON MICROSCOPY

Ву

Professor H. Fernandez-Moran, M.D., Ph.D. Committee on Biophysics University of Chicago Chicago 37, Illinois

Paper presented at ROYAL MICROSCOPICAL SOCIETY'S Celebration of the "Tercentenary of the Microscope in Living Biology" April 9, 1963

Bethesda, Maryland



Concept also in: Fernandez-Moran, H. (1965) *PNAS* 53: 445-451



"Cryo-Electron Microscope" concept

These "cryo-

electron microscopes", operating at temperatures of 1 to 4 degrees Kelvin, would embody the following significant features: (a) highly stable superconducting electromagnetic lenses, with very ripple-free magnetic fields of a persistent current in the optimum case; (b) operation in ultra-high vacuum and low temperatures resulting in decisive advantages of minimized specimen contamination, specimen damage and thermal noise; (c) optimum conditions for both low voltage (i.e. 1 to 10 kV) and high voltage electron microscopy. In addition, the use of highefficiency image viewing (single-crystal fluorescent screens) and recording devices operating at optimum low temperatures would make it possible to use high-speed cinematography and stroboscopic recording (e.g. obtained through pulsed T-F emission from pointed filaments) for attainment of high temporal resolution combined with high spatial resolution.

Complementary metal–oxide–semiconductor (CMOS) based detector (i.e, *K2 Summit*[™])



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Methods: Instrumentation



Direct Electron Detectors

Direct Detection Cameras

- Falcon (FEITM)
- K2 SummitTM (Gatan INC).

General Properties:

- High spatial resolution
- High Detective Quantum Efficiency (DQE)
- Higher sensibility than a CCD camera. Less electron dose required.



Dual-axis tilt tomography - FIB wedge E. coli BL21



Single-axis Tomogram B



- FEI TITAN Krios
- Direct electron detection (Falcon)
- Mag. 22.5kx

- Angular increment 3°
- Total Dose 2x ~50 e⁻/Å²
- Pix size: 0.372 nm/p
- Def. -9 µm



E. coli BL21 MtlA385-SecM







xy-slice from 3D reconstruction

3D-segmentation





Cryo-FIB: Molecular architecture of NPCs







From proteomic inventory to architecture



S. Nickell, C. Kofler, A. Leis, W. Baumeister: Nature Reviews Molecular Cell Biology 7 (2006) 225-230



More information...

Videos and Presentations:

• "Getting started in cryoEM" G. Jensen's Lab: <u>http://cryo-em-course.caltech.edu</u>

• Sjors Scheres' Lab at the MRC:

http://www2.mrc-lmb.cam.ac.uk/groups/scheres/impact.html

Book:



